

**INFORMATION DISCLOSURE CITATION
IN AN APPLICATION**
(Use several sheets if necessary)

PTO Form 1449

Atty Docket No. 113197-020	Application No. Unknown
Applicant Yamamoto, S., et al.	
Filing Date January 14, 2002	Group Unknown



U.S. PATENT DOCUMENTS

Examiner's Initials	Document Number	Publication Date	Inventor	Class	Subclass	Filing Date If Appropriate
MJS	3,993,939	11-23-76	Slavin et al.			
MJS	4,092,696	5-30-78	Boesen et al.			
MJS	4,823,230	4-18-89	Tiemann			
MJS	4,831,492	5-16-89	Kuisma			
MJS	4,838,088	6-13-89	Murakami			
MJS	5,186,054	2-16-93	Sekimura			
MJS	5,241,864	9-7-93	Addie et al.			
MJS	5,528,452	6-18-96	Ko			
MJS	5,585,311	12-17-96	Ko			
MJS	5,591,679	1-7-97	Jakobsen et al.			
MJS	5,706,565	1-13-98	Sparks et al.			
MJS	5,929,497	7-27-99	Chavan et al.			
MJS	5,936,164	8-10-99	Sparks et al.			
MJS	6,109,113	8-29-00	Chavan et al.			

FOREIGN PATENT DOCUMENTS

Examiner's Initials	Document Number	Publication Date	Country	Class	Subclass	Translation	
						Yes	No
MJS	11-326095	11-26-99	Japan				

Examiner's Initials	OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)
MJS	Seidel, H., et al., "Anisotropic Etching of Crystalline Silicon in Alkaline Solutions," J. Electrochem. Soc., Vol. 137, No. 11, November 1990, pp. 3626-3632.

Examiner: <i>Maurice Segal</i>	Date Considered: <i>10/11/02</i>
--------------------------------	----------------------------------

*Examiner: Initial if citation considered, whether or not citation is in conformance with PEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.